

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	)	
Hidekazu MIYAIRI et al.	)	Group Art Unit: 2828
Application No. 10/658,472	)	Examiner: Phillip Nguyen
Filed: September 10, 2003	)	Confirmation No. 4070
For: LASER APPARATUS, LASER IRRADIATION METHOD, AND MANUFACTURING METHOD OF SEMICONDUCTOR DEVICE	)	Date: May 29, 2007

**AMENDMENT**

**Mail Stop RCE**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed February 26, 2007, please amend the above identified application as follows.